

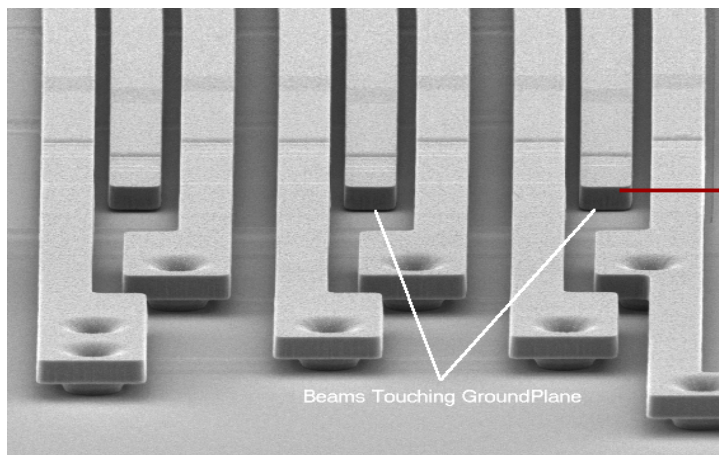


A stochastic multi-scale analysis for MEMS stiction failure

Truong-Vinh Hoang*, Ling Wu, Jean-Claude Golinval, Stéphane Paquay,
Maarten Arnst, Ludovic Noels

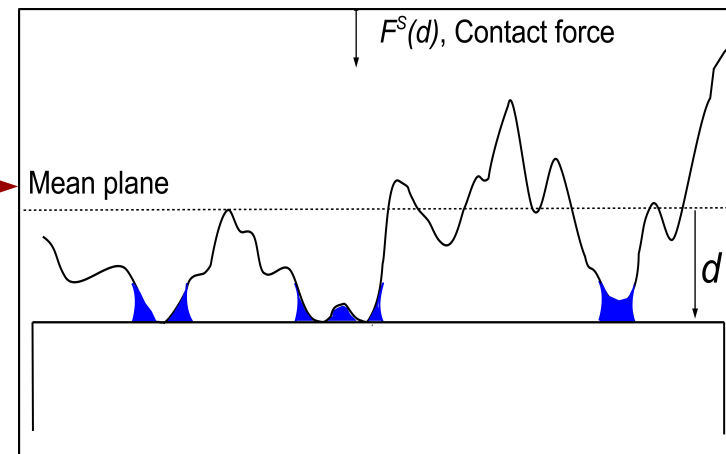
- 3SMVIB: The research has been funded by the Walloon Region under the agreement no 1117477 (CT-INT 2011-11-14) in the context of the ERA-NET MNT framework.
- (*) PhD candidate at the Belgian National Fund for Education at the Research in Industry and Farming (FNRS -FRIA).

- MEMS devices, e.g. accelerometers, digital mirrors, pressure sensors, resonators
 - Successfully applied in the industry. E.g. accelerometers for air bag systems
- Stiction**: a common failure of MEMS
 - Due to dominance of surface adhesive forces at the micrometer scale
 - E. g., van der Waals forces and capillary forces
 - In humid conditions, the **capillary forces** are dominant
 - Depends on the surface topologies
 - The physical contact happens at the **high asperities**



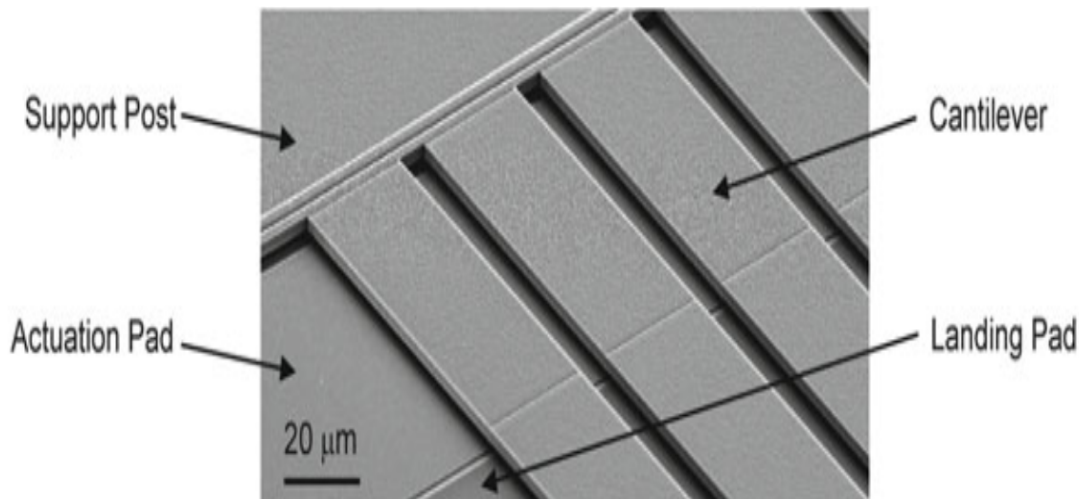
Stiction failure in a MEMS sensor

(Jeremy A.Walraven Sandia National Laboratories. Albuquerque, NM USA)



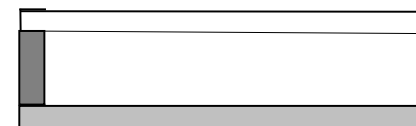
Water condensing between two surfaces

- MEMS devices, e.g. accelerometers, digital mirrors, pressure sensors, resonators
 - Successfully applied in the industry. E.g. accelerometers for air bag systems
- Stiction**: a common failure of MEMS
 - Due to dominance of surface adhesive forces at the micrometer scale
 - E. g., van der Waals forces and capillary forces
 - In humid conditions, the **capillary forces** are dominant
 - Depends on the surface topologies
 - The physical contact happens at the **high asperities**
 - An **uncertain phenomenon**: [Boer et al. 2007, 2013], [W. M. van Spengen 2003, 2015]
 - e.g. Stiction test: Some beams are stuck with different configurations, other beams are released

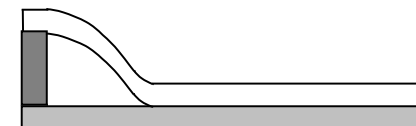


Cantilever beams array

[Boer et al. 2013]



free beam

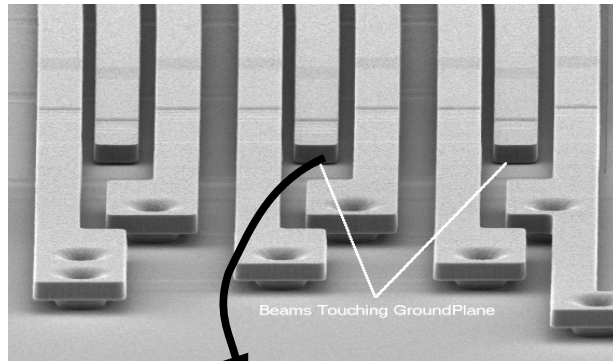


failure beam
high adhesive energy

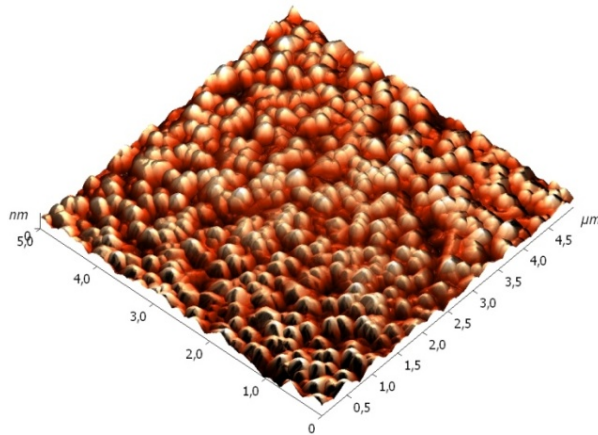
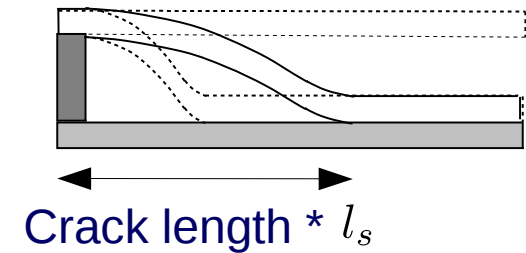


failure beam
lower adhesive energy

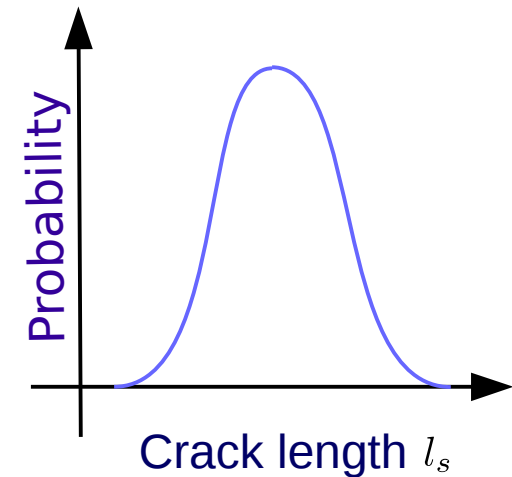
- Construct a **numerical model** for **micro cantilever beam structures**
 - To predict the **crack length** l_s and **its uncertainties** from the surface topology
 - At an **acceptable computational cost**



Reality



Numerical model



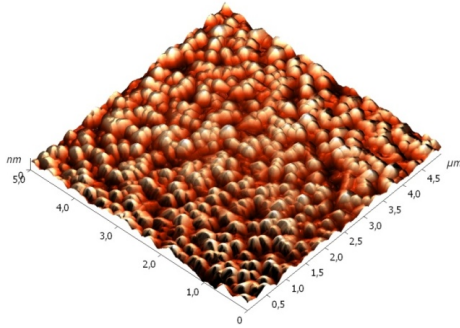
Atomic Force Measurements (**AFM**)
of **contact surfaces**

Crack length distribution

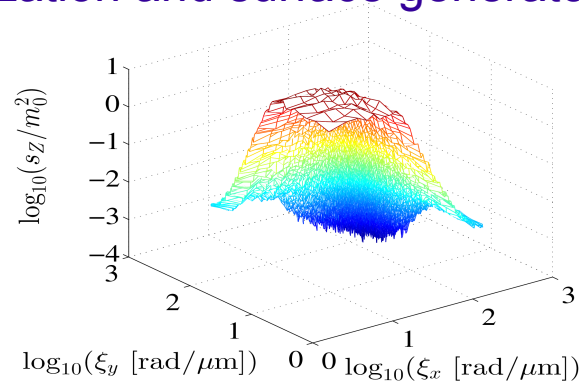
* The **crack length** l_s characterizes the **required energy to release** the cantilever beam out of the failure configuration

- Multiscale model
- Probabilistic multiscale model
 - Direct Monte-Carlo multiscale method (high computational cost)
 - Stochastic model-based multiscale method (acceptable computational cost)
- Numerical results: comparison, evaluation
- Conclusions and perspectives

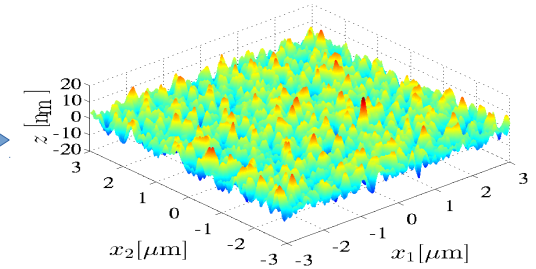
- Lower scale:** surface characterization and surface generator



AFM measurements



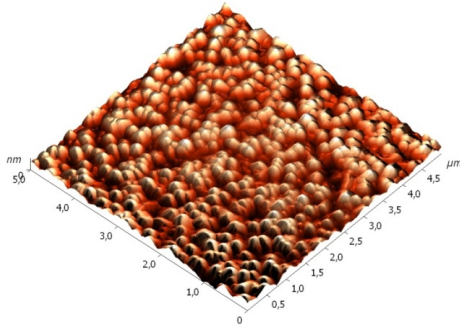
Topology spectral density



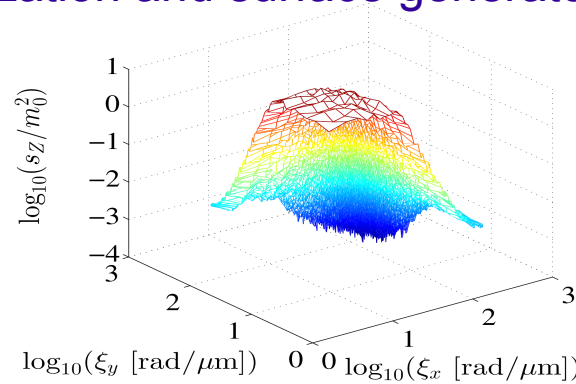
Generated surface

- Meso-scale:** evaluate the contact forces by a semi-analytical contact model
- Upper-sale:** Integrate the contact forces as contact law into FE model

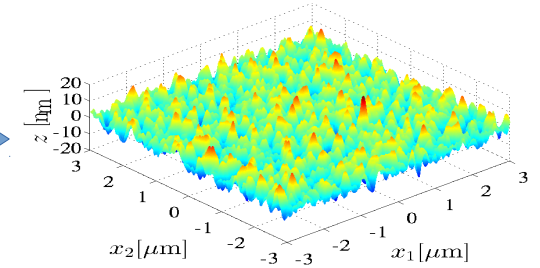
- Lower scale:** surface characterization and surface generator



AFM measurements



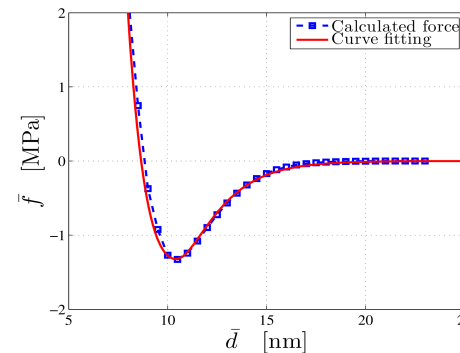
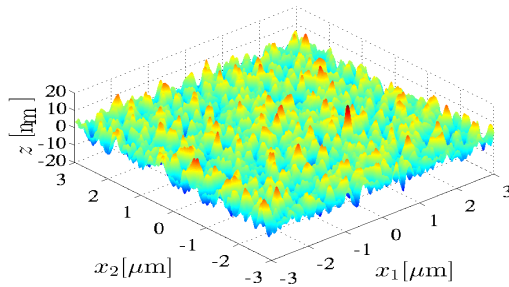
Topology spectral density



Generated surface

- Meso-scale:** evaluate the contact forces by a semi-analytical contact model

Generated surface

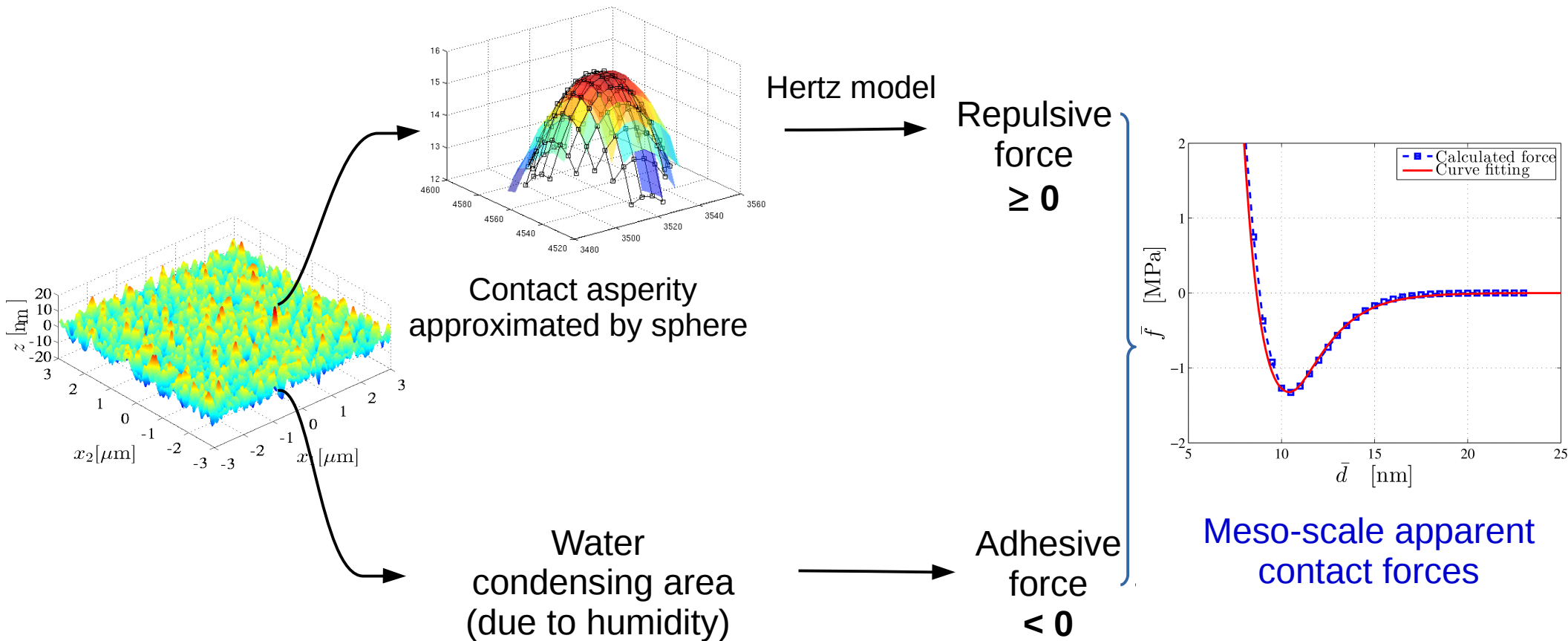


Apparent adhesive
Contact forces

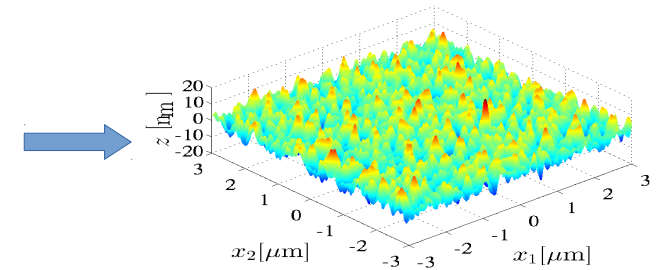
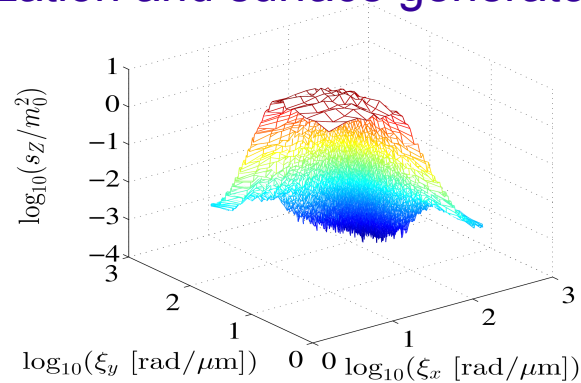
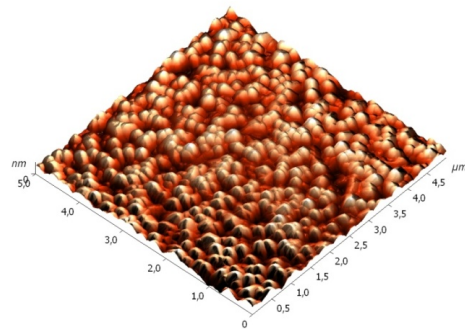
- Upper-sale:** Integrate the contact forces as contact law into FE model

- Semi-analytical contact model for adhesive contact problem**

- Based on DMT spherical asperity contact model
- Rough surface contact model

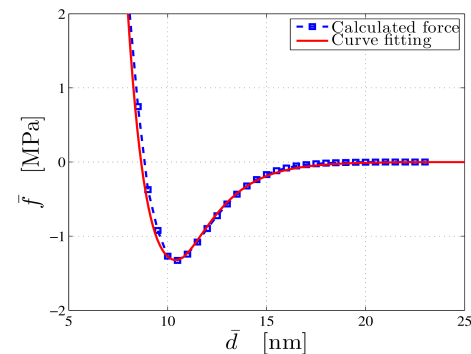
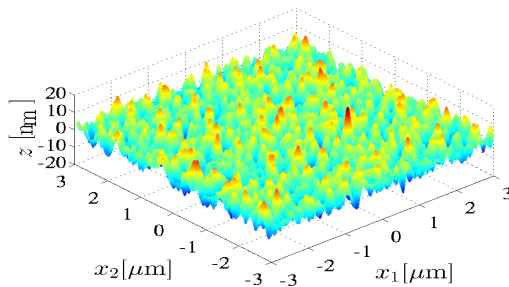


- Lower scale:** surface characterization and surface generator

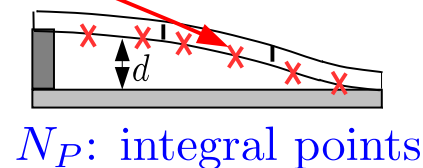
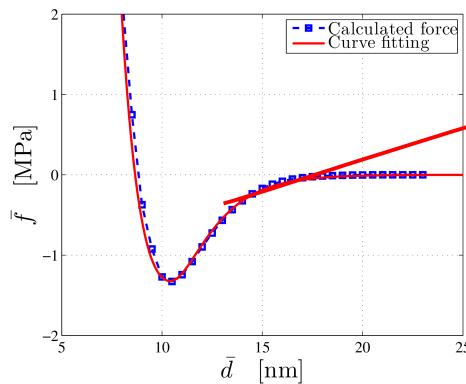


- Meso-scale:** evaluate the contact forces by a semi-analytical contact model

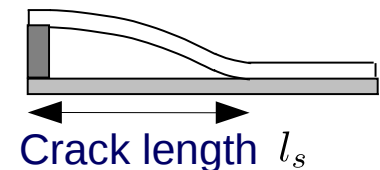
Generated surface



- Upper-sale:** Integrate the contact forces as contact laws into a FE model



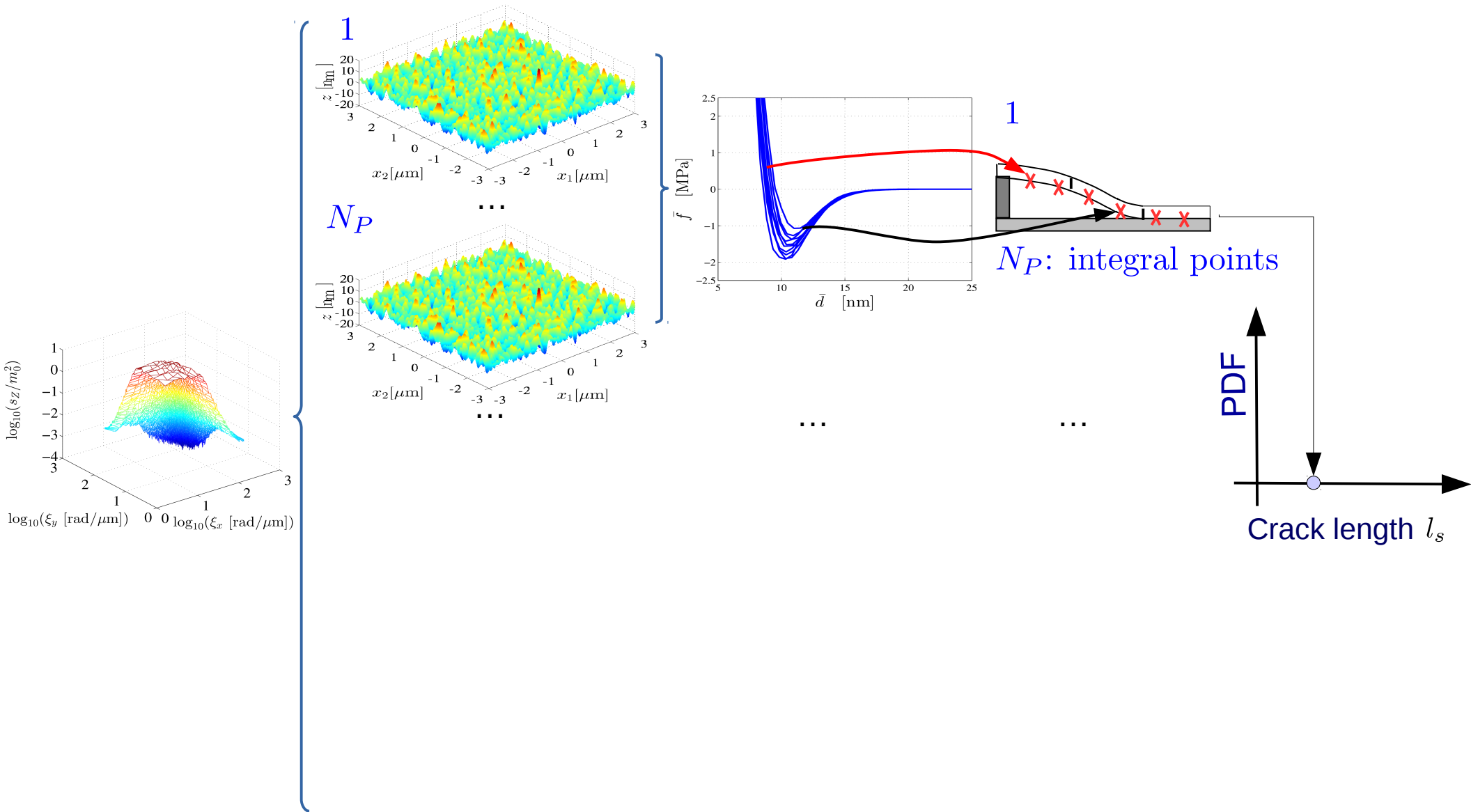
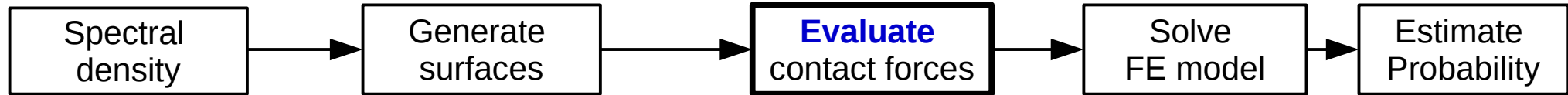
FE model

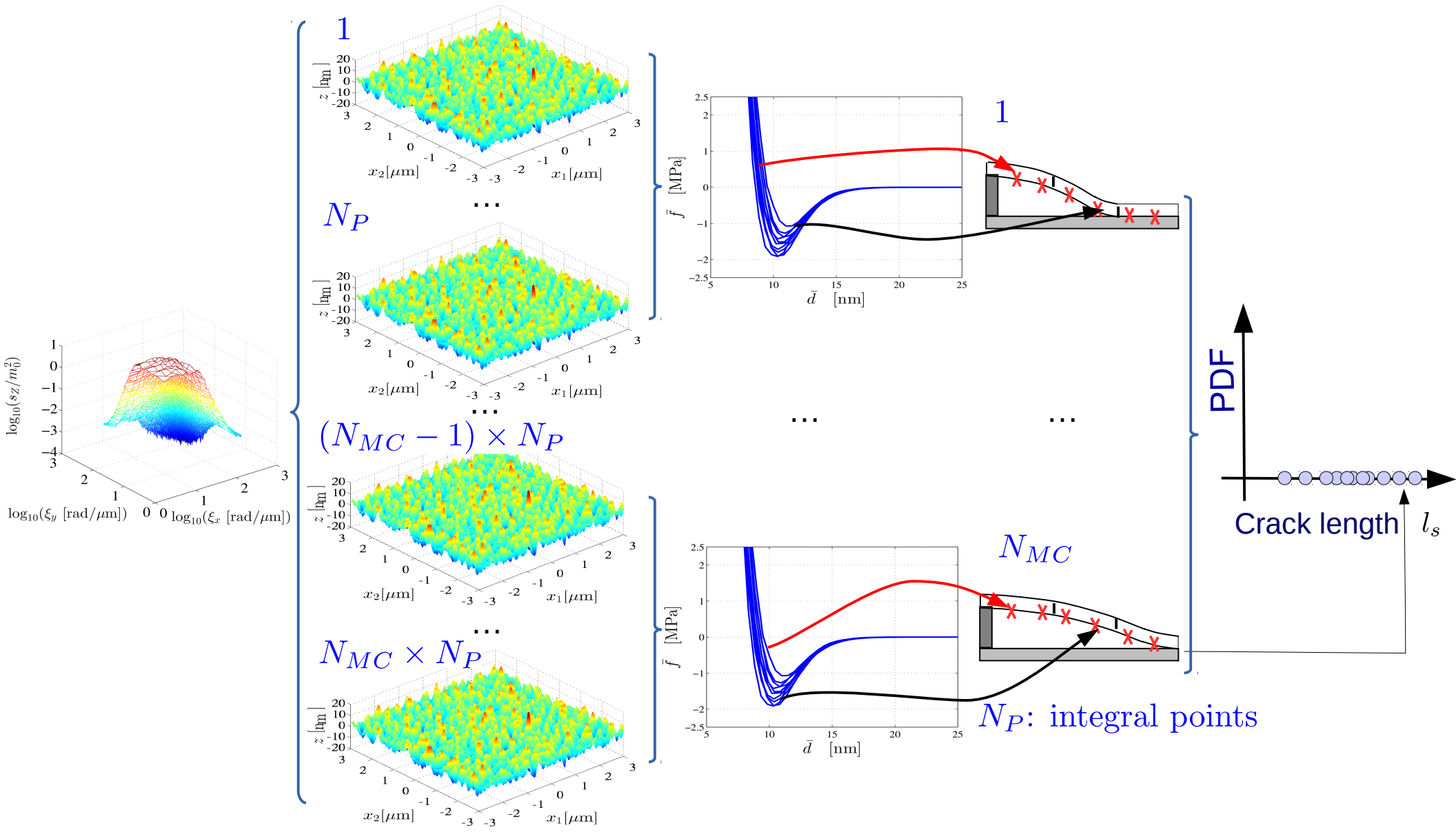
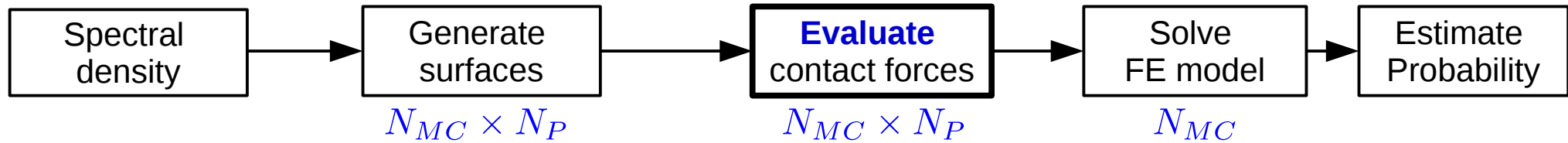


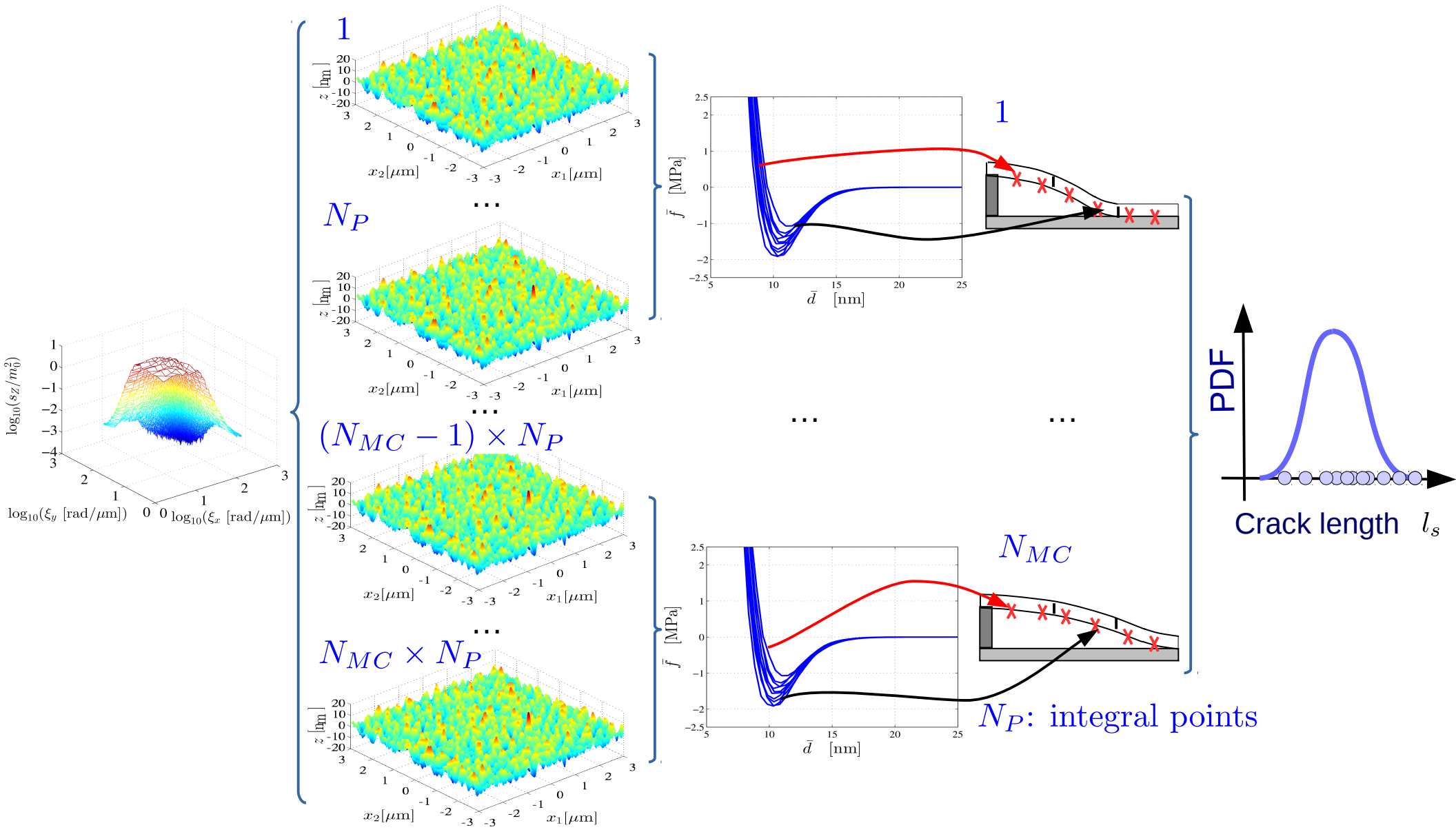
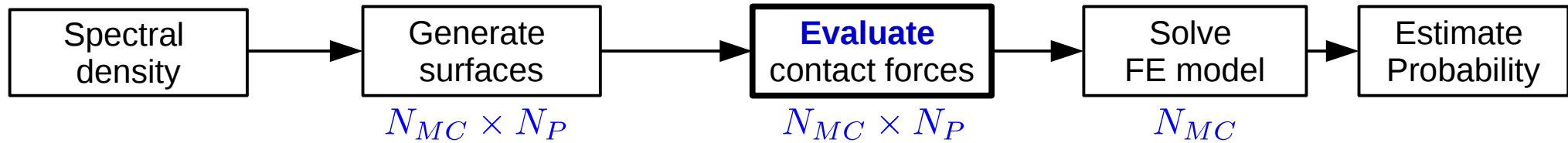
Stiction failure

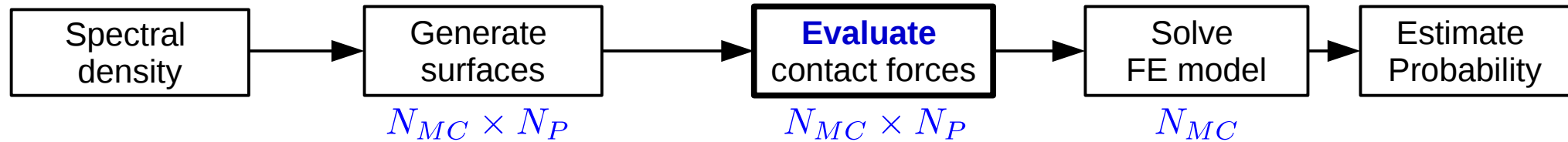
Direct Monte-Carlo multiscale method

10

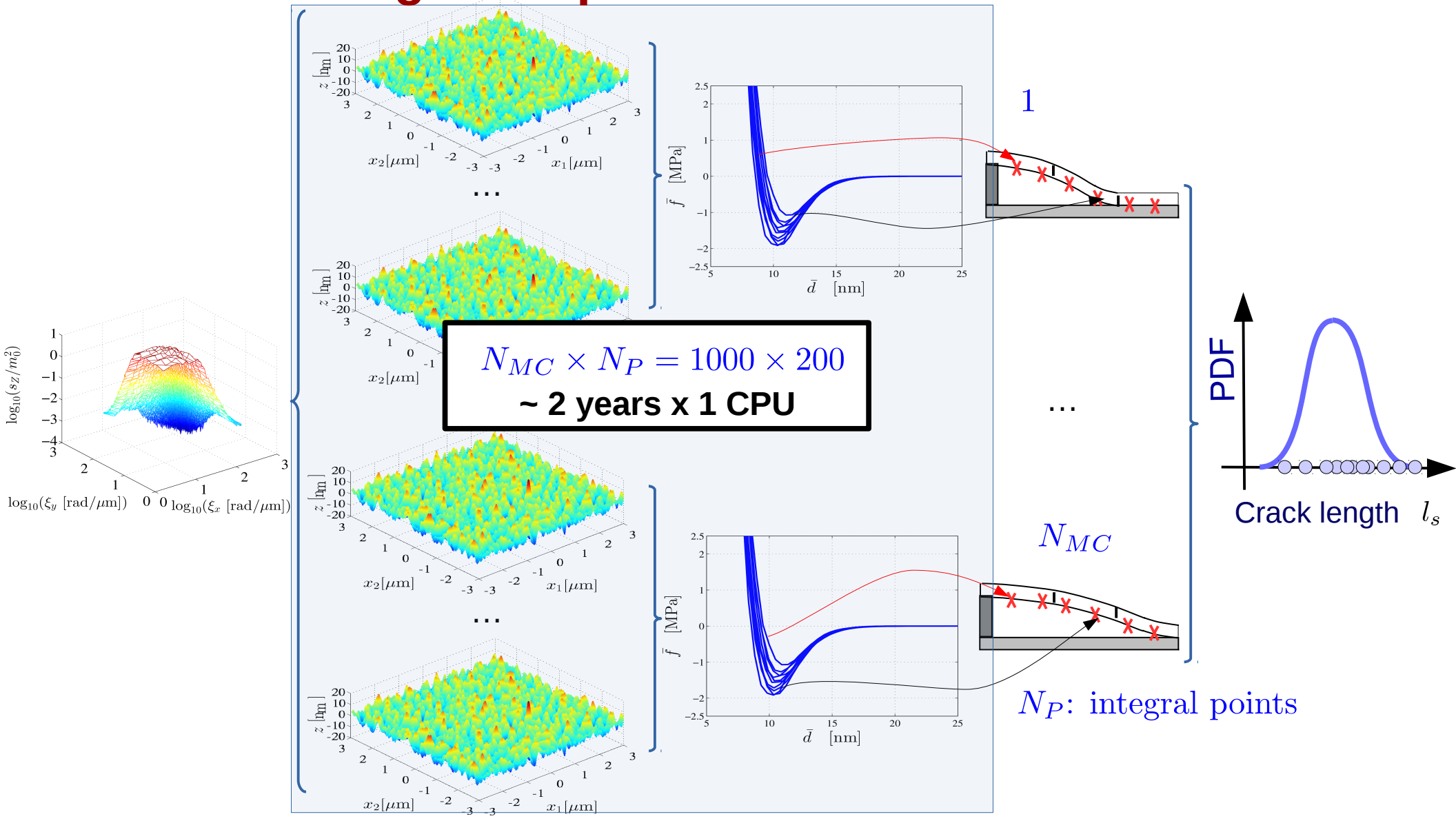




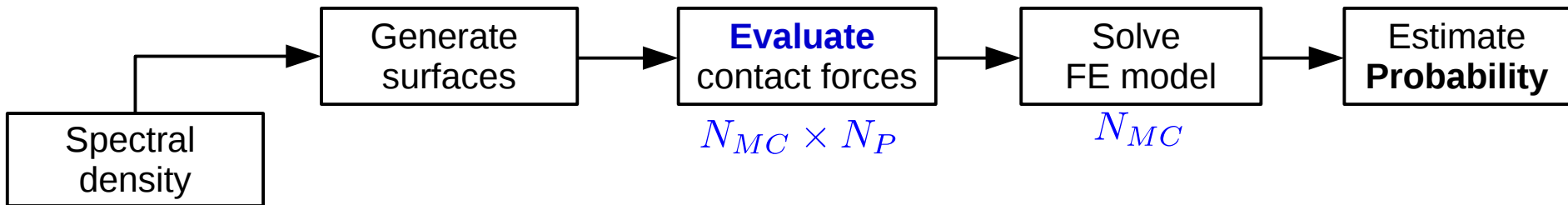




High computational cost

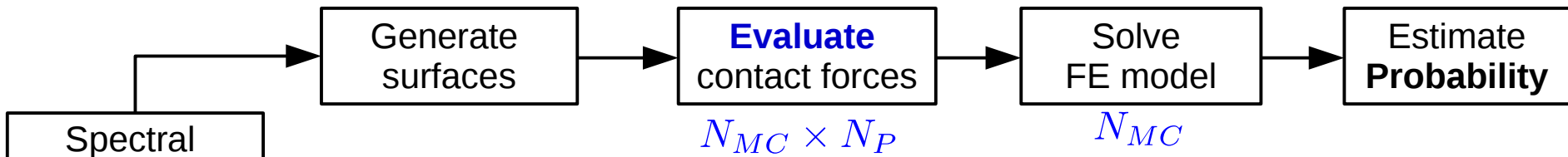


- Direct Monte-Carlo multiscale method (**high computational cost**)

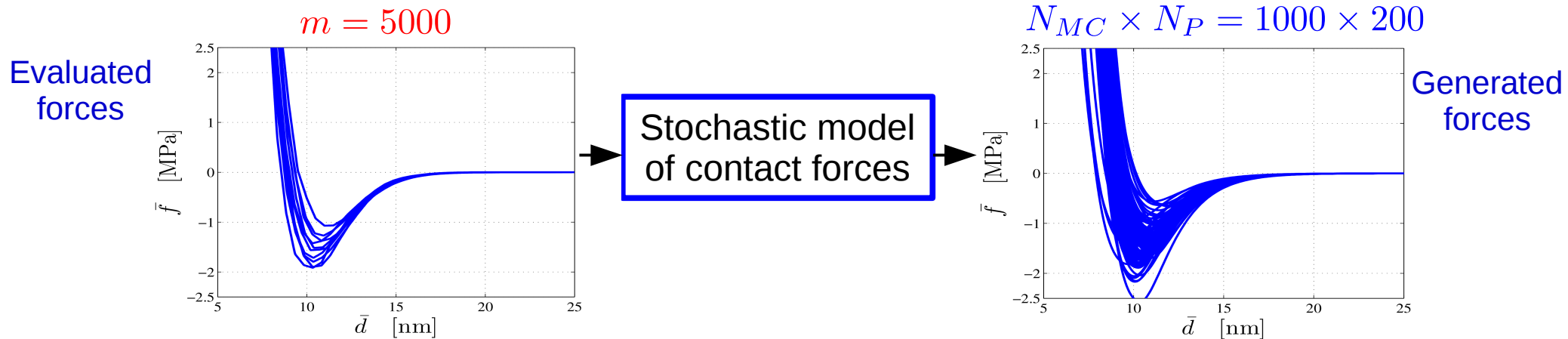
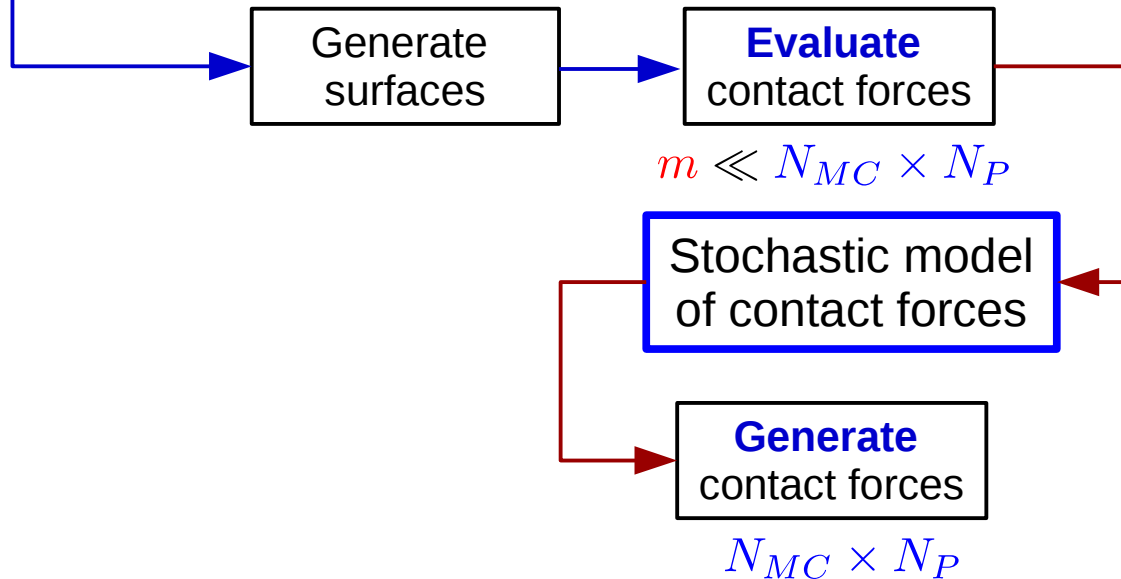


- Stochastic model-based multiscale method (**acceptable computational cost**)

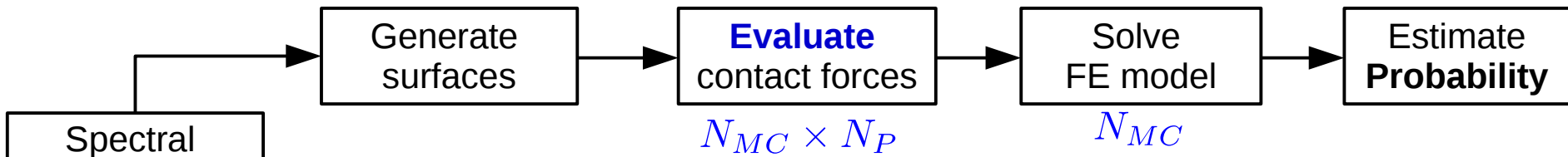
- Direct Monte-Carlo multiscale method (**high computational cost**)



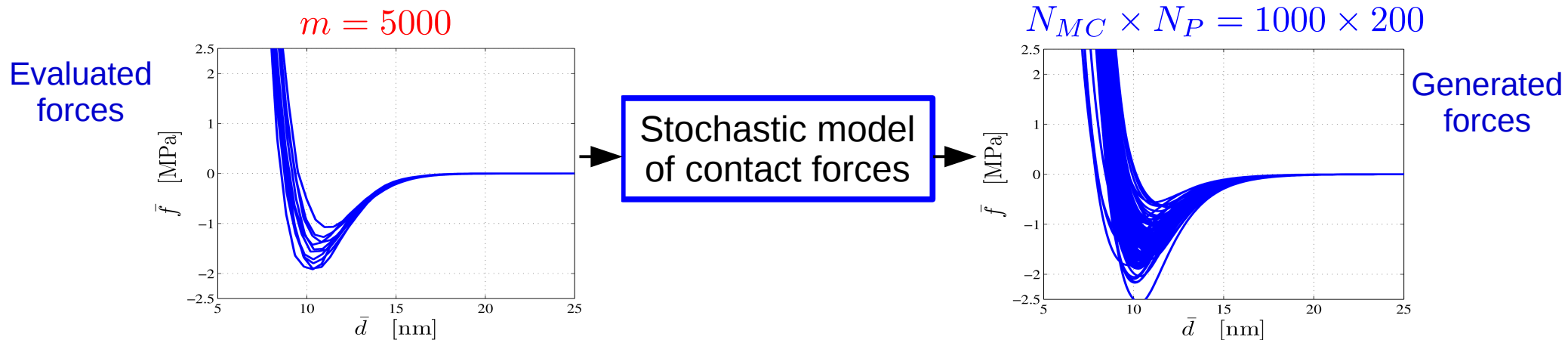
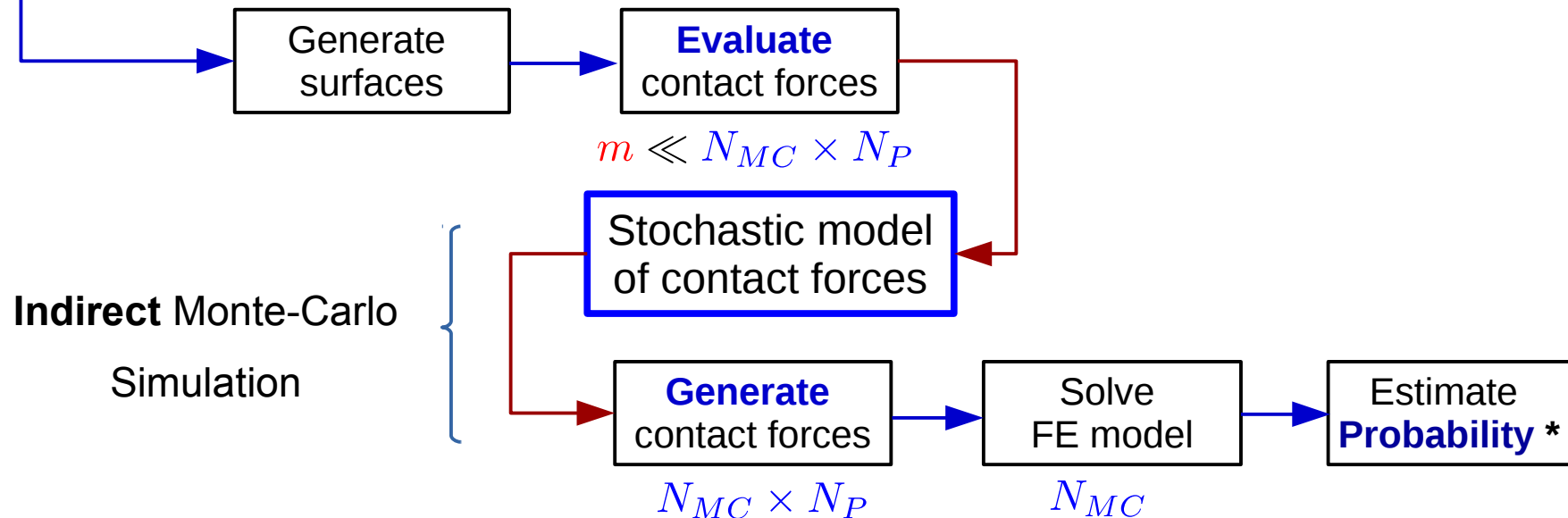
- Stochastic model-based multiscale method (**acceptable computational cost**)



- Direct Monte-Carlo multiscale method (**high computational cost**)



- Stochastic model-based multiscale method (**acceptable computational cost**)



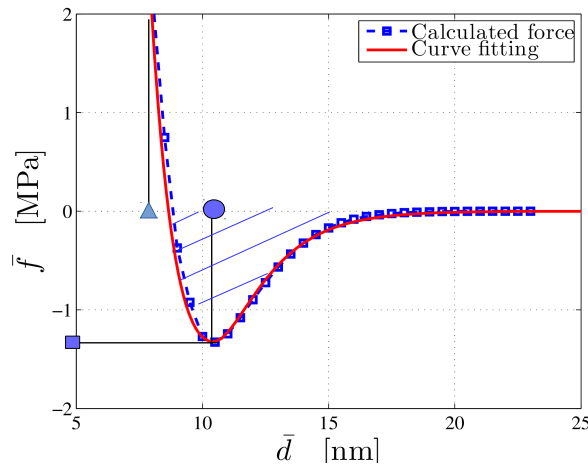
- Stochastic model for apparent contact forces: *generalized polynomial chaos expansion (gPCE)*
 - Parameterization** of the apparent contact force using a **modified Morse potential**

$$\bar{f}(\bar{d}) = \Phi(\bar{d}; \mathbf{v})$$

Curve fitting
function

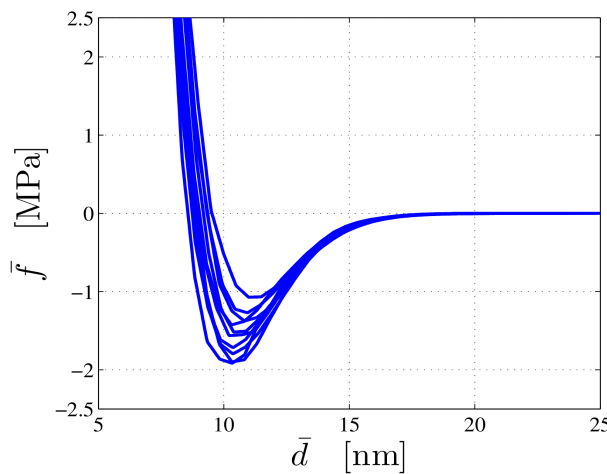
Parameters
vectors

Force-distance
curves



Parameterization

$$\mathbf{v} = \begin{pmatrix} \bar{f}_{\max} \\ \bar{e} \\ \bar{d}_{\max} \\ \bar{d}_{\text{limit}} \end{pmatrix}$$



Parameterization

$$\{\mathbf{v}^{\{1\}}, \dots, \mathbf{v}^{\{m\}}\}$$

- Stochastic model for apparent contact forces: *generalized polynomial chaos expansion (gPCE)*

- Parameterization

$$\bar{f}(\bar{d}) = \Phi(\bar{d}; \mathbf{v}) \quad \text{Input data: } \{\mathbf{v}^{\{1\}}, \dots, \mathbf{v}^{\{m\}}\}$$

- Representing the parameters vectors by a **truncated gPCE model: order N_d**

$$\mathbf{v} \stackrel{\text{d.}}{\approx} \mathbf{v}^{gPCE}(\xi | N_d) = \sum_{\alpha=1}^N \mathbf{c}_{\alpha} \Psi_{\alpha}(\xi).$$

$\Psi_{\alpha}(\xi)$: Legendre polynomials order $\leq N_d$
 ξ : Uniformly distributed random vector
 \mathbf{c}_{α} : Coefficients to be identified
 $\stackrel{\text{d.}}{\approx}$: approximately distribution

- The higher the order N_d , the better the approximation
- The coefficients are identified by the projection of the iso-probabilistic transformation on the polynomial chaos system

$$\mathbf{c}_{\alpha} : \text{Distribution}(\{\mathbf{v}^{\{1\}}, \dots, \mathbf{v}^{\{m\}}\}) \simeq \text{Distribution}(\mathbf{v}^{gPCE})$$

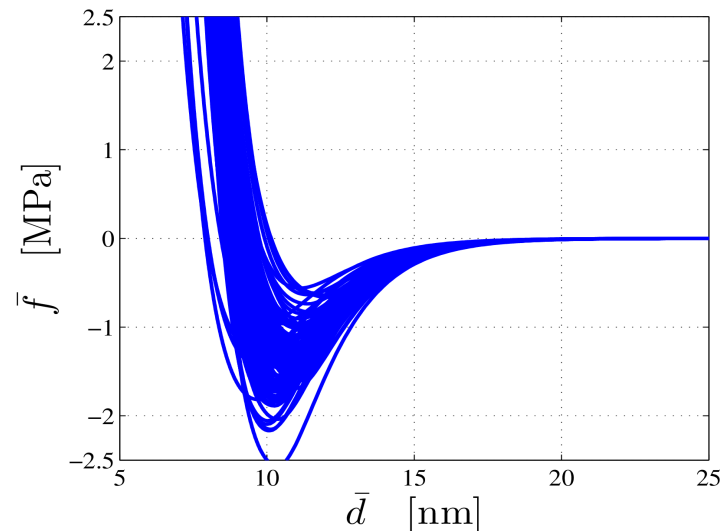
- Stochastic model for apparent contact forces: *generalized polynomial chaos expansion (gPCE)*
 - Generate apparent contact forces**

$$\bar{f}(\bar{d}) = \Phi(\bar{d}; \mathbf{v})$$

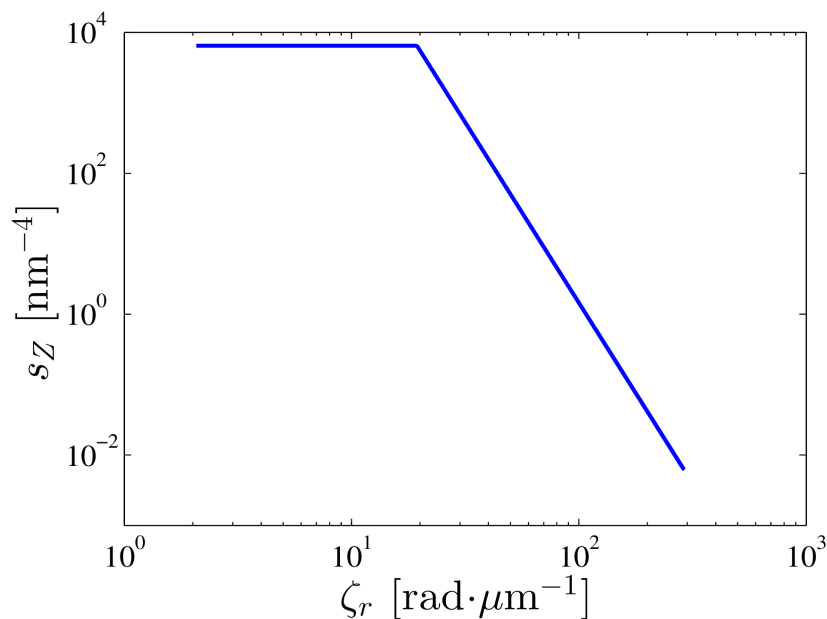
$$\mathbf{v} \stackrel{\text{d.}}{\sim} \mathbf{v}^{gPCE}(\xi | N_d) = \sum_{\alpha=1}^N \mathbf{c}_{\alpha} \Psi_{\alpha}(\xi).$$

Sampling
Uniformly distributed
random vector

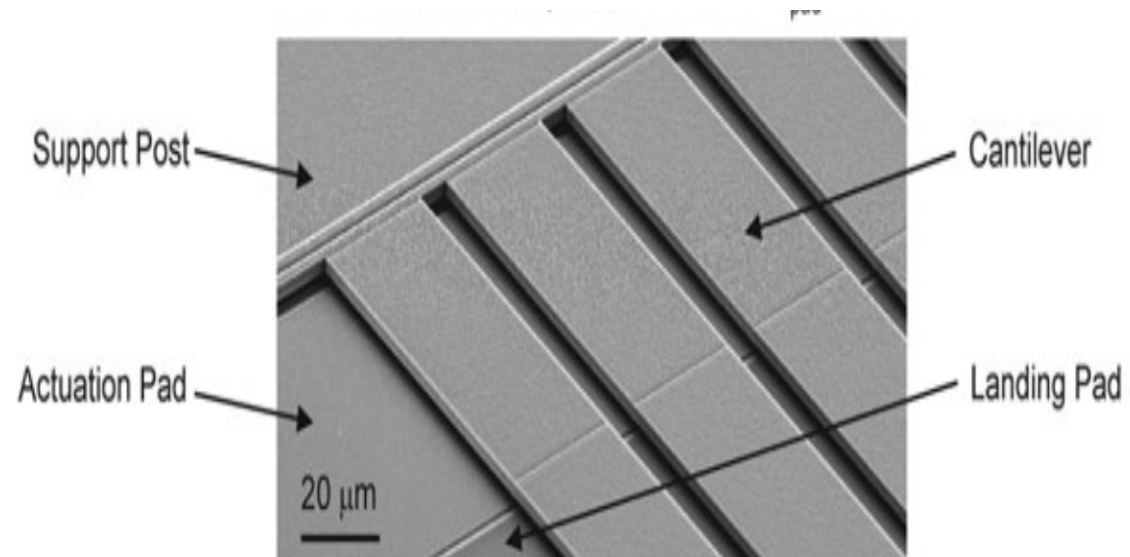
Generated apparent
contact forces



- Using the two methods: direct Monte-Carlo multiscale vs Stochastic-model based multiscale method to evaluate
 - Distribution of apparent contact forces parameters
 - Distribution of crack lengths
- Input: a constructed *isotropic self-affine spectrum density* function of the contacting surfaces based on *experiments* report in [Boer et al. 2013]

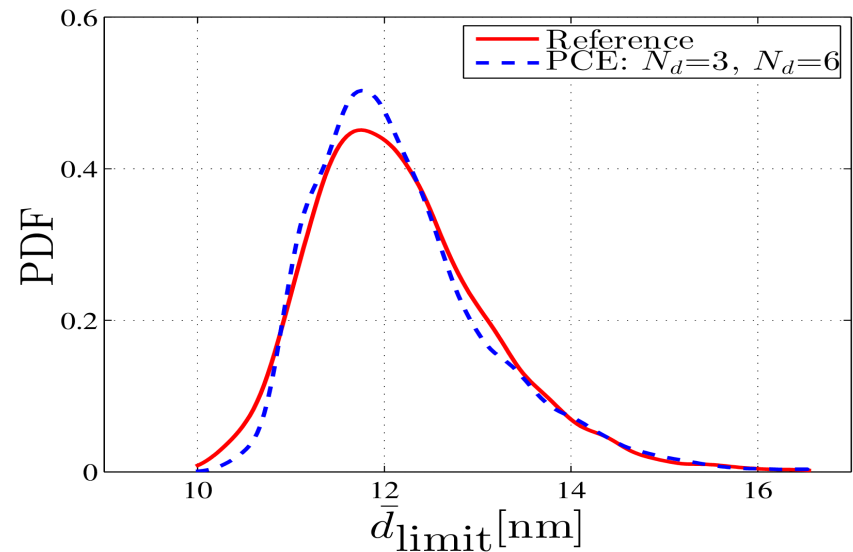
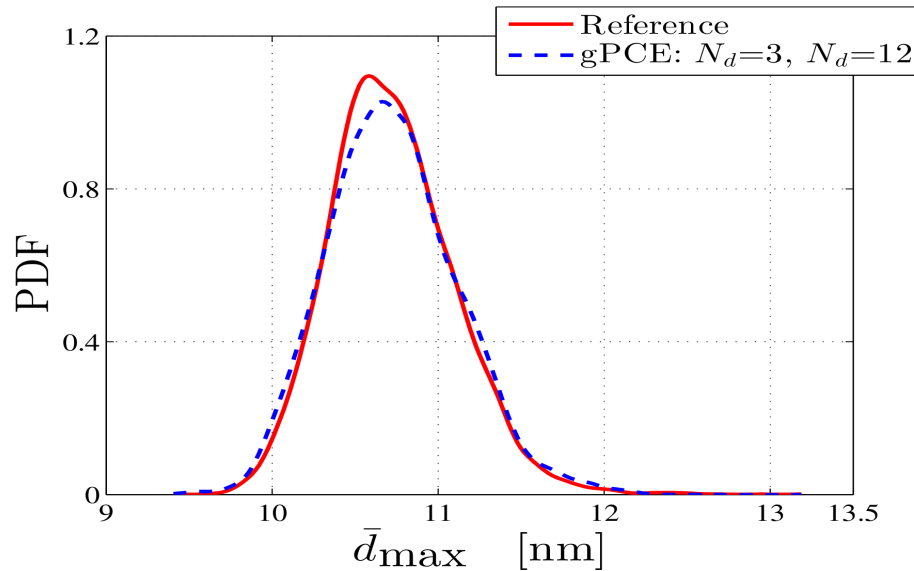


Isotropic self-affine spectrum density

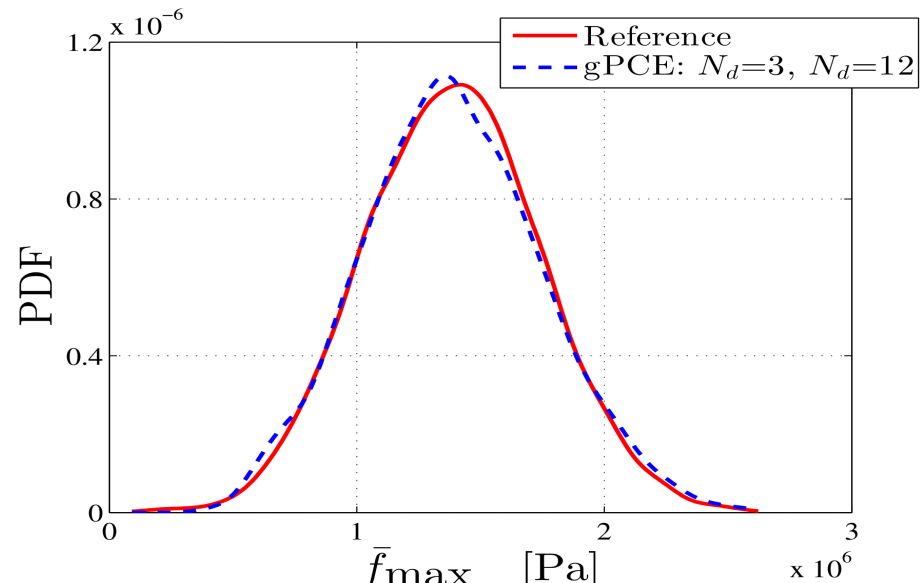
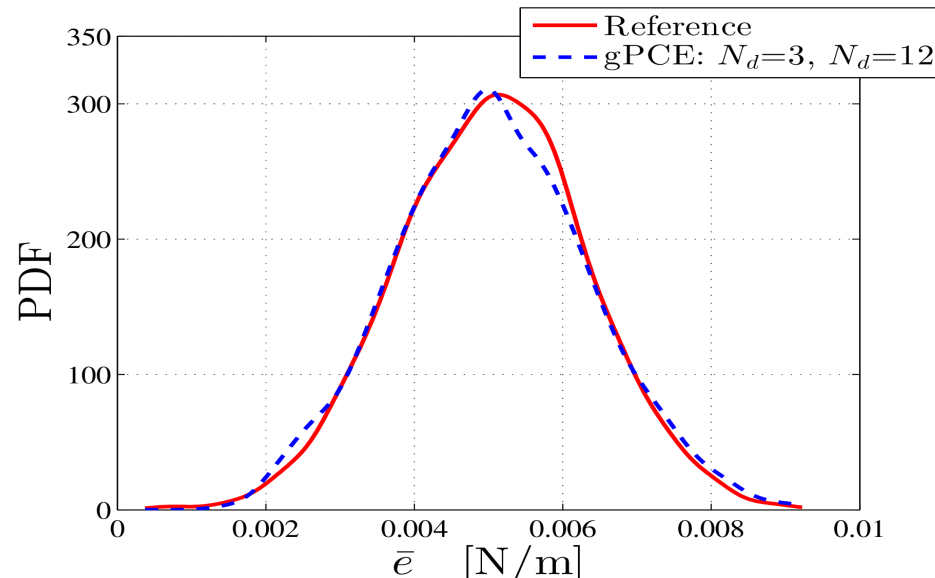


Cantilever beams array
[Boer et al. 2013]

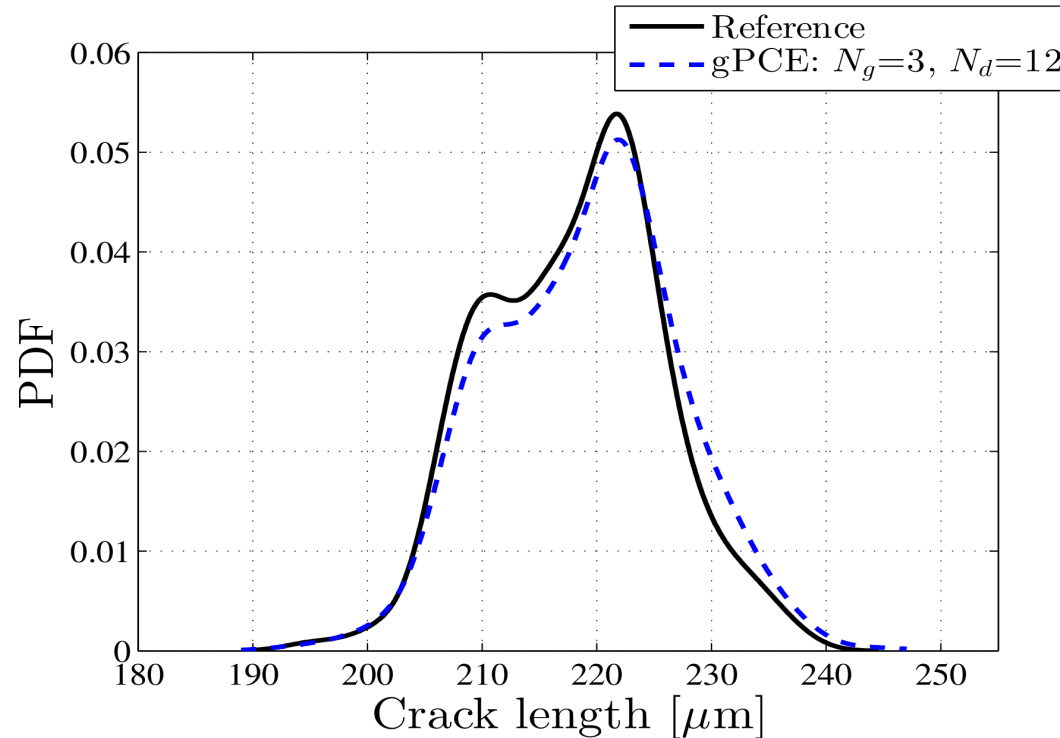
- Direct Monte-Carlo multiscale vs Stochastic-model based multiscale method
- Distribution of contact forces parameters
 - The stochastic model-based method **approximates well the probabilistic distribution of the apparent contact forces**



Humidity
85%

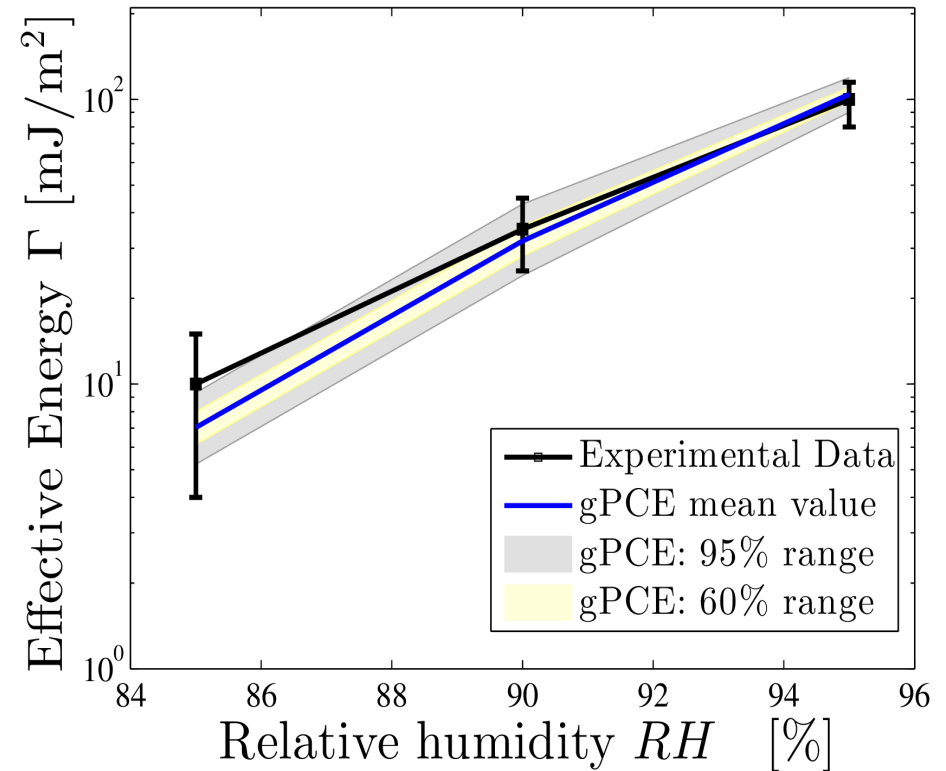
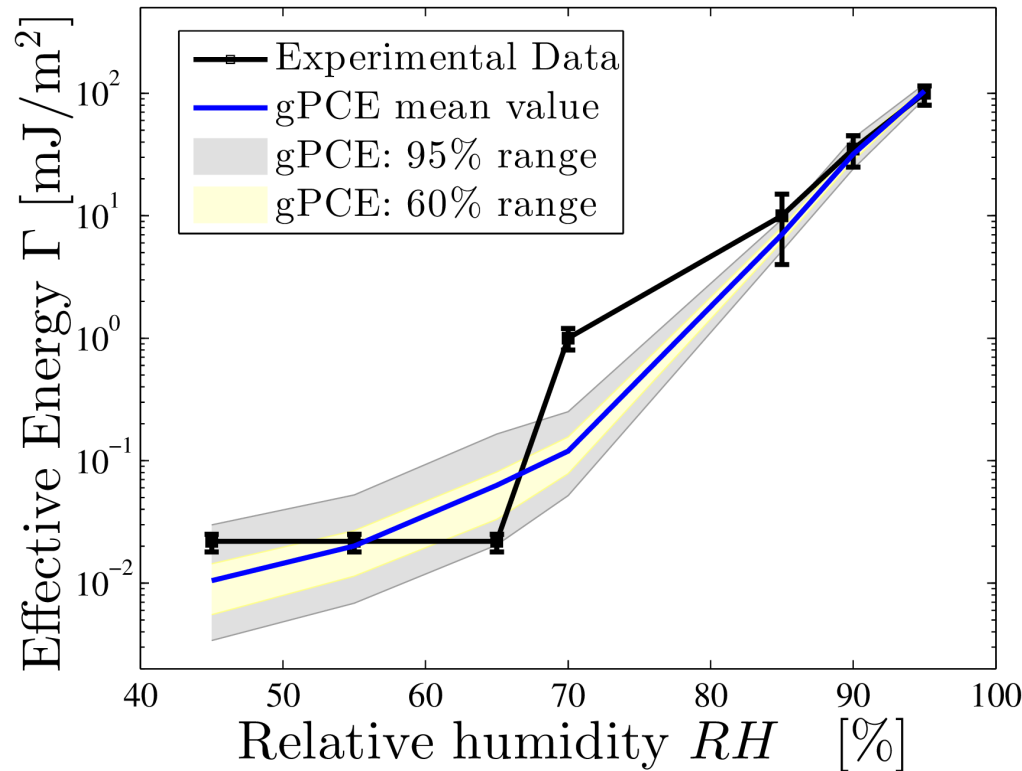


- Direct Monte-Carlo multiscale vs Stochastic-model based multiscale method
- Distribution of crack lengths
 - The stochastic model-based method **approximates well the probabilistic distribution of the crack lengths**



- Computational efficiency: **Time to evaluate 1 realization in one CPU:**
 - Direct Monte-Carlo method: **~16 hours** (due to the evaluation of the apparent contact forces)
 - Stochastic model-based method: **~ 5 minutes.**
 - To obtain the distribution: **1000 realizations are required**
- **Good approximation and acceptable computation cost**

- Validation: comparison with experimental results [Boer et al. 2013]
 - Accurate prediction of the experimental results at high humidity levels
 - At low humidity levels:
 - The van der Waals forces need to be accounted for
 - The rough surface needs to be directly measured



$$\Gamma = \frac{3}{2} E \frac{h^2 t^3}{l_s^4}, \quad \longrightarrow \text{Crack lengths}$$

- A **Stochastic model-based multiscale method for stiction problems** taking the surface topology into account by
 - Using **spectral density** to characterize the AFM surface measurements and generate numerical surfaces
 - Using **multi-scale approach**, and a **semi-analytical contact model**
 - To define and evaluate the **meso-scale apparent contact forces**
 - To integrate them as **contact laws to FE model**
 - Applying **gPCE** to build a **stochastic model** of the **random meso-scale contact forces**
 - To reduce efficiently the **computational cost**
- The model is **validated** by a comparison with **experimental results**
- Applying the model to evaluate the **failure percentage** of MEMS designs such as
 - The stiction of MEMS accelerometers under shock
 - The stiction of MEMS gears system



Documents can be downloaded at:

www.ltas-cm3.ulg.ac.be

<http://www.sandia.gov/mstc/mems/>

- T.-V. Hoang et al., *A computational stochastic multi-scale methodology for mems structures involving adhesive contact. (submitted to Tribology International)*
- T.-V. Hoang et al., *A probabilistic model for predicting the uncertainties of the humid stiction phenomenon on hard materials*
- L Wu et al., *A micro–macro approach to predict stiction due to surface contact in microelectromechanical systems*
- W. Merlijn van Spengen, *MEMS reliability from a failure mechanisms perspective*
- M. de Boer, *Capillary adhesion between elastically hard rough surfaces*
- F. W. DelRio et al. *Van der waals and capillary adhesion of polycrystalline silicon micromachined surface*
- F. Poirion, C. Soize, *Numerical Methods and Mathematical Aspects For Simulation of Homogeneous and Inhomogeneous Gaussian Vector Fields*
- A. Clément, C. Soize, J. Yvonnet, *Uncertainty quantification in computational stochastic multiscale analysis of nonlinear elastic materials*
- C. Soize, R. Ghanem, *Physical Systems with Random Uncertainties: Chaos Representations with Arbitrary Probability Measure*
- C. Desceliers, R. Ghanem, C. Soize, *Maximum likelihood estimation of stochastic chaos representations from experimental data*
- M. Arnst, R. Ghanem, C. Soize, *Identification of Bayesian posteriors for coefficients of chaos expansions*
- S. Das et al., *Polynomial chaos representation of spatio-temporal random fields from experimental measurements*
- D. W. Scott, *Multivariate Density Estimation: Theory, Practice, and Visualization*

Thank you for your attention